

**Notice of References Cited**

Application/Control No.

10/040,042

Applicant(s)/Patent Under

Reexamination

SU, WEI-YU

Examiner

Zeinab E. EL-Arini

Art Unit

1746

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**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-5,472,516	12-1995	Hanson et al.	134/18
	B	US-5,152,878	10-1992	Datta et al.	205/717
	C	US-5,695,896	12-1997	Pierrat, Christophe	430/5
	D	US-6,139,993	10-2000	Lee et al.	430/5
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Werner Kern (The Evolution of Silicon Wafer Cleaning Technology), J. Electrochem. Soc., Vol. 137, No. 6, June 1990, Pages 1887-1891.
	V	
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)

Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.